

Docket No.: 21776-00052-US1  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Nobuhiro Miki et al.

Confirmation No.: 6222

Application No.: 10/614,244

Filed: July 8, 2003

Art Unit: 1734

For: RESIST FILM REMOVAL APPARATUS AND  
RESIST FILM REMOVAL METHOD

Examiner: Mark. A. Osele

OK to Enter

MCB 6-29-06

**AMENDMENT AFTER FINAL ACTION UNDER 37 C.F.R. 1.116**

MS AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

**INTRODUCTORY COMMENTS**

In response to the Final Office Action mailed April 10, 2006, finally rejecting claims 3, 4, 23, 26-34, please amend the above-identified U.S. patent application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 4 of this paper.

No fees are believed to be due with this amendment.